

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	206	257/617.ccls.	USPAT	OR	OFF	2005/04/07 15:29
L2	404	257/618.ccls.	USPAT	OR	OFF	2005/04/07 15:29
L3	1477	257/347.ccls.	USPAT	OR	OFF	2005/04/07 15:29
L4	68	257/913.ccls.	USPAT	OR	OFF	2005/04/07 15:30
L5	110	257/611.ccls.	USPAT	OR	OFF	2005/04/07 15:31
L6	29	mun-young\$.in. kim-kun\$.in. koh-chung\$.in. pyi-seung\$.in.	USPAT	OR	OFF	2005/04/07 15:31
L7	31	mun-young\$.in. kim-kun\$.in. koh-chung\$.in. pyi-seung\$.in.	US-PGPUB	OR	OFF	2005/04/07 15:31
L8	35	mun-young\$.in. kim-kun\$.in. koh-chung\$.in. pyi-seung\$.in.	EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/04/07 15:32
L9	432	denud\$6 and defect\$6 and (wafer substrate)	USPAT	OR	ON	2005/04/07 15:33
L10	339	denud\$6 and defect\$6 and (wafer substrate)	US-PGPUB	OR	ON	2005/04/07 15:33
L11	81	denud\$6 and defect\$6 and (wafer substrate)	EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/07 15:34
L12	14279	bulk and defect\$6 and (wafer substrate)	USPAT	OR	ON	2005/04/07 15:35
L13	2311	12 and (bulk same defect\$6)	USPAT	OR	ON	2005/04/07 15:35
L14	296	13 and (bulk adj2 defect\$6)	USPAT	OR	ON	2005/04/07 15:35
L15	10098	bulk and defect\$6 and (wafer substrate)	US-PGPUB	OR	ON	2005/04/07 15:35
L16	153	15 and (bulk adj2 defect\$6)	US-PGPUB	OR	ON	2005/04/07 15:36
L17	391	bulk and defect\$6 and (wafer substrate)	EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/07 15:35
L18	308	17 and (bulk same defect\$6)	EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/07 15:36